



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki SATO

Application No.: 10/594,458

Filed: September 26, 2006

For: METHOD FOR EVALUATING CRYSTAL
DEFECTS OF SILICON WAFER



Group Art Unit: 1792

Examiner: L. VINH

Docket No.: 129546

MAIL STOP RCE

**LARGE ENTITY REQUEST FOR
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicant(s) hereby request(s)
continued examination.

☒ Applicant(s) further request(s) entry and consideration of the attached submission.

The above-identified application was filed on or after June 8, 1995. Thus, entry is proper
under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 215095 in the amount of ☒ \$810.00 as payment of the fees
set forth in 37 C.F.R. §1.17(e). The Commissioner is hereby authorized to charge any additional fees
or credit any overpayment associated with this communication to Deposit Account No. 15-0461.

Respectfully submitted,

William P. Berridge
Registration No. 30,024

Nicolas A. Brentlinger
Registration No. 62,211

WPB:NAB/kjl

Date: February 11, 2009

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Alexandria, Virginia 22320-4850
Telephone: (703) 836-6400

**DEPOSIT ACCOUNT USE
AUTHORIZATION**

Please grant any extension
necessary for entry;
Charge any fee due to our
Deposit Account No. 15-0461

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